

PATENT 0756-2077

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of:

Shunpei YAMAZAKI et al.

Application No.:

09/466,828

Filed:

December 20, 1999

For:

INSULATING FILM AND

METHOD OF PRODUCING SEMICONDUCTOR DEVICE

Art Unit:

2818

Examiner:

R. BERRY

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on 11-21-00

The The

## AMENDMENT UNDER 37 C.F.R. 1.111

Assistant Commissioner of Patents Washington, D.C. 20231

November 21, 2000

Dear Sir:

In response to the Examiner's non-final Office Action mailed June 21, 2000, the period for responding having been extended two (2) months, please consider the following amendments and remarks in connection with the above-identified application.

## **IN THE CLAIMS:**

Please amend claims 2, 10, 13, 14, and 18 as follows:

2. (Amended) A method according to claim 1, wherein the halogen is [fluoring or]

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chlorine.

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